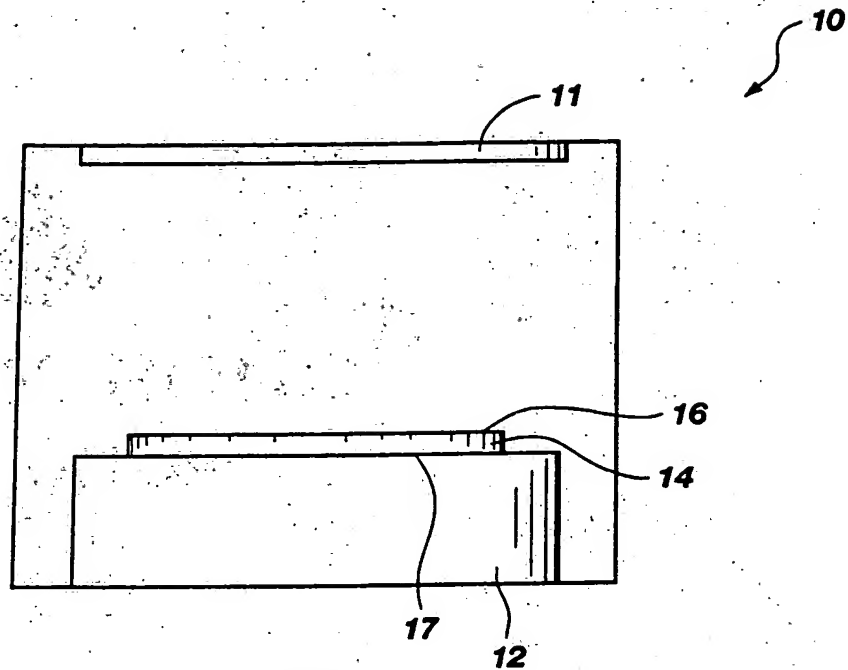


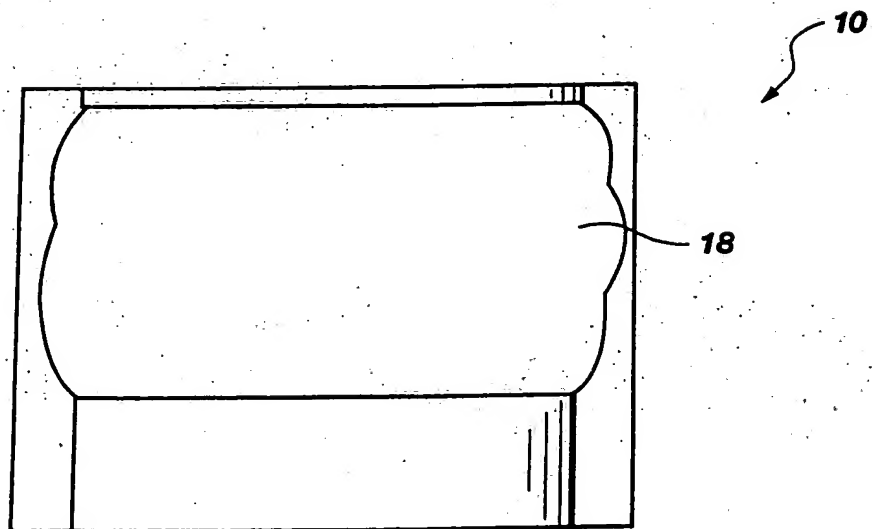
TITLE: METHOD OF DECONTAMINATING PROCESS  
CHAMBERS, METHODS OF REDUCING DEFECTS IN ANTI-  
REFLECTIVE COATINGS, AND RESULTING SEMICONDUCTOR  
STRUCTURES

Inventor: Zhiping Yin  
Docket No.: 3657.5US

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**Fig. 1**

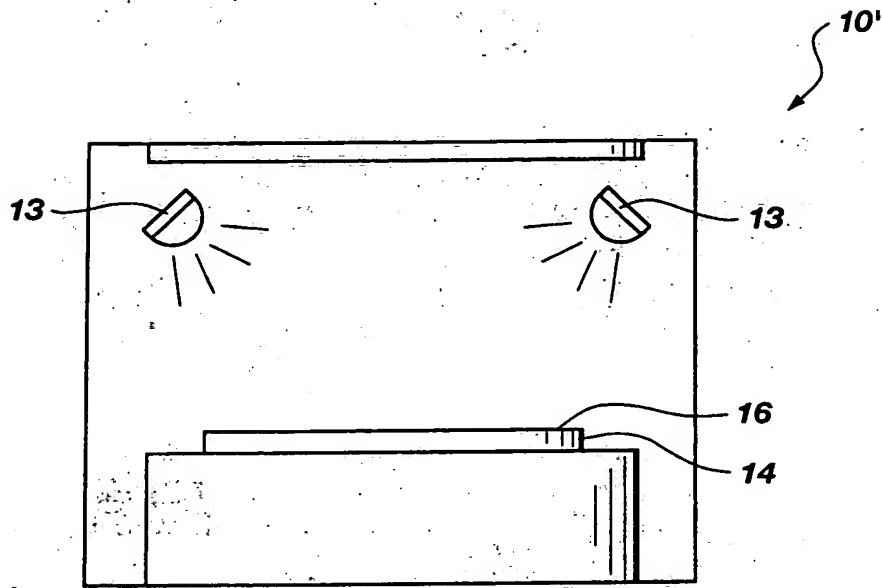


**Fig. 2**

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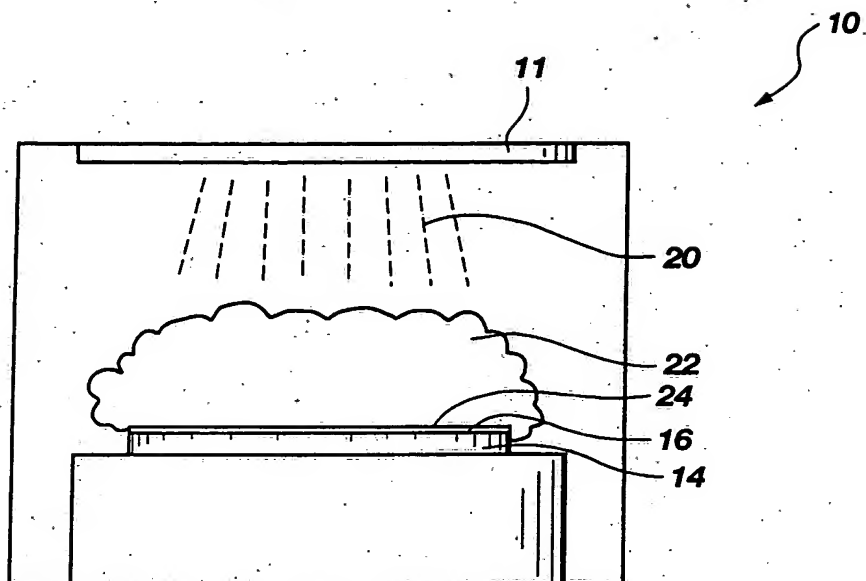


**Fig. 1a**

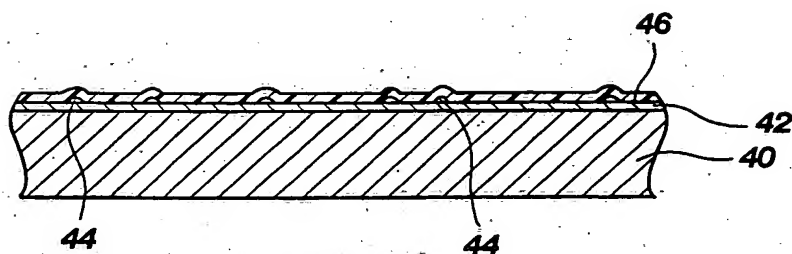
TITLE: METHOD OF DECONTAMINATING PROCESS  
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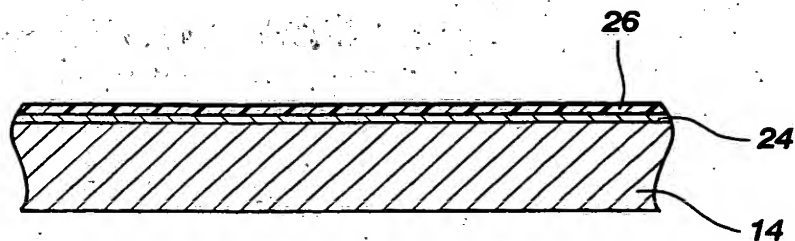
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**Fig. 3**



**Fig. 4**  
**(PRIOR ART)**

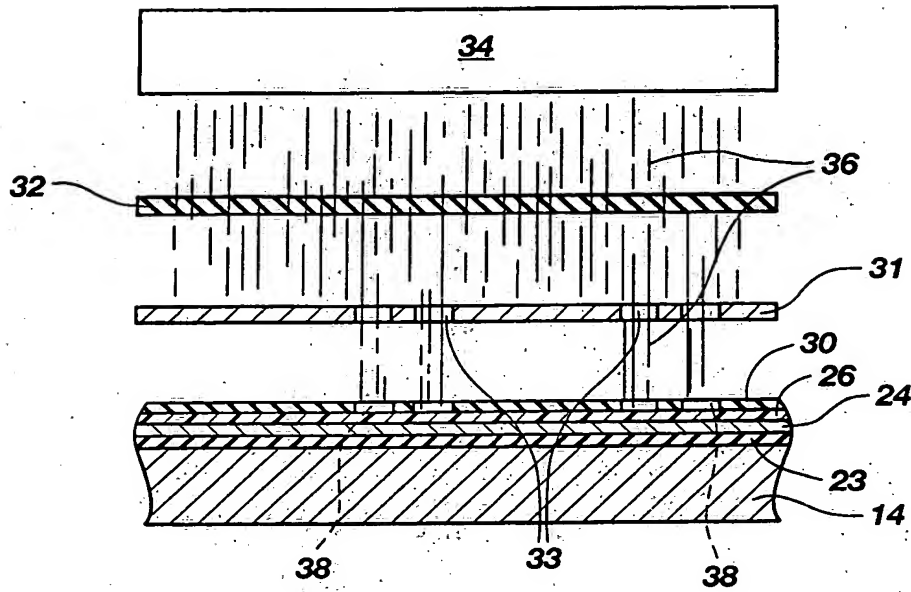


**Fig. 5**

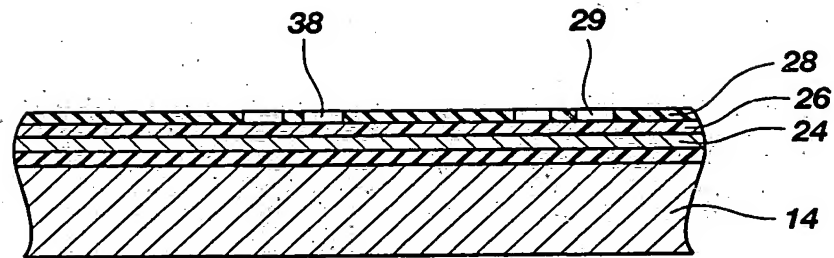
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**Fig. 6**



**Fig. 7**